

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Vishwanathan et al.

Application No.: 09/608,537

Filed: June 30, 2000

Title: POLISHING PADS FOR CHEMICAL

MECHANICAL PLANARIZATION

Group Art Unit:

Examiner: M. Guerrero

Attorney Docket No.: 126

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Assistant Commissioner for Patents Washington, D.C. 20231

## **AMENDMENT AND ELECTION**

Sir:

Please amend the application as follows: Cancel claims 30-46 subject to refiling in a divisional application in response to a requirement for restriction.

## **REMARKS**

Election is made hereby to prosecute the invention of Group I, with claims 1-29, and 47-52 readable thereon. The requirement for restriction is traversed hereby, because the apparatus claims and method claims capable of practice by the apparatus are based on the same disclosure and the same field of search by the USPTO, and in the interest of patent law harmonization, the USPTO should not stand alone for requiring different patents for such patent claims.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.

Date of Deposit: Decmeber 10, 2001

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Respectfully submitted, Arun Vishwanathan et al.

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